

Simulation of a low voltage organic transistor compatible with printing methods

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Abstract—The use of printing methods to deposit organic semiconductors promises to enable low cost electronics. However, printing processes deposit thick and amorphous semiconductor layers that result in poorly performing Organic Field Effect Transistors (OFETs) that generally are not appropriate for incorporation into commercially viable circuits. Another undesirable property of OFETs is their high operating voltage (~40 V). Organic Metal-Semiconductor Field-Effect Transistors (OMESFETs) are proposed as alternatives to OFETs for use with printing methods. OMESFETs operate at low voltages (~5 V), and are expected to show better on/off current ratios than OFETs in a thick film semiconductor.

Simulations of OFETs and OMESFETs are performed assuming regioregular poly (3-hexylthiophene) (rr-P3HT) as the amorphous semiconductor layer with localized states close to the band edge. The results of the simulations show a current ratio of 10^4 in the OMESFET, and of 700 in the OFET for a 400 nm thick semiconductor layer. Because the OMESFET operates in the depletion mode, versus the accumulation mode in the OFET, the calculated mobility in the OMESFET is two orders of magnitude smaller than that in the OFET. Simulations suggest that the OMESFET design offers performance advantages over printable OFETs, where low voltage operation is demanded.

Index Terms—Organic Field-Effect Transistor (OFET), Organic Metal-Semiconductor Field-Effect Transistor (OMESFET), regioregular poly (3-hexylthiophene) (rr-P3HT), Organic Schottky junction.

I. INTRODUCTION

POTENTIALLY simple and easy methods of fabricating organic electronic devices including inkjet printing [1], micro-contact printing [2] and roll-to-roll printing [3], have promised very low cost electronic products compared to the lithography methods in silicon

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technology. In spite of relatively rapid progress in the last decade in the development of new organic electronic materials and fabrication processes [4], making a printed OFET with reasonable electronic characteristics remains a serious challenge [5]. This challenge arises from a contradiction between the fabrication methods and the electrical characteristics of the organic semiconductors. On the one hand, to enhance the performance of the device very thin layers of semiconductor [6] and insulator [7] are necessary. Also, the molecular order of the semiconductor at the interface between the insulator and the semiconductor is very critical [8]. On the other hand, printing methods produce relatively thick and non-uniform layers of the materials and result in amorphous molecular structure [2, 9]. In this paper we first review the operation modes in an OFET and the challenges to achieve reasonable performance with printing methods. Then the structure of an OMESFET and its compatibility with low-cost fabrication techniques are discussed. The charge transport in organics is also reviewed. The electrical characteristics of a simulated OFET and an OMESFET are then presented.

The simulation work presented is intended to provide guidance and motivation for the experimental implementation of the OMESFET. The results point to both the possibilities and the limitations of this design, as well as to methods of optimizing device performance.

II. BACKGROUND

A. OFET

Because of the similarities between amorphous and organic semiconductors, the Thin-Film Transistor (TFT) structure, used in amorphous silicon, has also been used in building OFETs. Fig. 1 shows a schematic of an OFET. In an OFET the gate electrode is separated from the channel by an insulator. The drain and source electrodes make ohmic contacts with the semiconductor layer.

Most OFETs work in either the depletion or accumulation modes [10]. In the accumulation mode, which turns the transistor on, excess carriers are accumulated at the interface between semiconductor and insulator by applying a sufficiently high voltage to the gate electrode (voltage larger than the threshold). The accumulated layer, with a thickness of less than a few nanometers [11],

provides a highly conductive path between the drain and source [12]. As a result, the output conductance of the OFET increases. When the voltage between the drain and the source terminals, V_{DS} , is low, the drain current, I_D , changes linearly with the gate voltage as [10]:

$$I_D = \left(\frac{Z\mu_f C_i}{L}\right)[(V_{GS} - V_T)V_{DS}] \quad (1)$$

where C_i is the capacitance of the insulating layer per unit of area, μ_f is the field-effect mobility of carriers in the channel, V_{GS} is the gate source voltage, and V_T is the threshold voltage. Z and L are channel width and length, respectively.

When V_{DS} is larger than $V_{GS} - V_T$ the drain current saturates. Then [10]:

$$I_D = \left(\frac{Z\mu_f C_i}{2L}\right)(V_{GS} - V_T)^2 \quad (2)$$

Equation 1 is often used to calculate the threshold voltage and the field-effect mobility from the slope and the voltage intercept of the I_D - V_{GS} plot in an OFET.

In order to turn off the transistor the depletion mode is usually applied. In this mode, the gate has to repel carriers not only from the channel but also from the entire thickness of the semiconductor [12]. Therefore, the on/off current ratio drops with increasing in the bulk conductivity and/or the thickness of the semiconductor [13].

Building OFETs from very lightly doped semiconductors [14] and reducing the semiconductor layer thickness to a few nanometers [13] maximizes bulk resistance. Unfortunately, deposition of a nanometers-thick layer with current printing methods, such as micro-contact printing or inkjet printing, results in very thick and poor quality films [2, 9]. Also, printing methods need soluble organic materials, and in these the background doping of the semiconductor is usually at a medium level ($\sim 10^{16} \text{ cm}^{-3}$) [12]. Often the application of very low doped small organic molecules with a more accurate deposition method like vapor deposition is preferred to obtain high performance in OFETs [10], but the fabrication method is as expensive as those applied in amorphous silicon TFTs.

Also, most OFETs operate over voltage ranges in excess of 20V [15]. Such a wide voltage range limits the application of OFETs in low-cost products, particularly if they are battery operated. To reduce the voltage range the gate capacitance must be increased [16]. The simplest way of doing this is to decrease the thickness of the insulating layer (to a few tens of nanometers); however, this again is challenging using current printing technology [17].

B. OMESFET

In this paper, the OMESFET structure is proposed as a low-voltage transistor for use with printing methods. The

organic MESFET has been demonstrated as a low-voltage, thick-film (a few micrometers) organic transistor once before [18]. OMESFETs work only in the depletion mode, and similar to Junction Field-Effect Transistors (JFETs), the cross section of the channel in the bulk part of the semiconductor layer is controlled by the depletion region extending from the gate electrode [19]. Fig. 2 depicts the proposed geometry for the OMESFET. Although an instance of the OMESFET has been reported, and low voltage operation demonstrated, the performance described was otherwise poor or undetermined. The question posed in this research is what performance can be expected of the OMESFET?

In an OMESFET, the depletion region results from a Schottky contact between the gate electrode and the semiconductor. Schottky contacts between organic semiconductors and metals have been studied extensively [20] and have been applied in Organic Light Emitting Diodes (OLEDs) [21] and organic solar cells [22]. In a transistor, conventional device models suggest that if the thickness of the semiconductor layer, a , is larger than the depth of the depletion region, W , a conductive path is open between the drain and the source and the transistor is on. At very low V_{DS} the drain current is expressed as [23]:

$$I_D = G_0 \frac{(a - W)}{a} V_{DS} \quad (3)$$

where G_0 is the maximum conductance (in the absence of the depletion region) [23]:

$$G_0 = q\mu_b N \frac{Z}{L} a \quad (4)$$

where q is the unit charge, μ_b is the bulk mobility and N is the doping density. For larger V_{DS} the depletion depth is not uniform along the channel and it is deeper close to the drain contact. Again following conventional device theory, it is expected that at large enough drain to source voltages the depletion region pinches off and the current saturates. Also the depth of the depletion region can be controlled by V_{GS} which results in a control on the drain current. Reverse biasing the Schottky junction extends the depletion region and causes a lowering of drain current. Eventually at the pinch-off voltage the transistor turns off. The semiconductor thickness determines the pinch-off voltage and the saturation current in OMESFETs. In crystalline semiconductors W is proportional to the square root of the applied voltage across the Schottky contact [19]. Therefore the drain current can be well characterized versus V_{GS} . In contrast, the depletion width in organic semiconductors is not simply expressed and depends on the density of states and the doping density. In such a case, simulation of the device is required to obtain the device parameters. Nevertheless, the current is proportional to G_0 . Hence, the

conductance of the transistor in the on mode increases with the semiconductor thickness and the doping density. Such a fact is, indeed, an advantage for printing methods, which use soluble organics and have poor control on the film thickness. The printing of various materials including organic semiconductors [2], metals [24, 25], and conducting polymers [1] has been demonstrated.

A further advantage is the lack of an insulating layer in the OMESFET which leads to a simpler fabrication process than that in the OFET. There are only three basic steps in the OMESFET fabrication: patterning the drain and source contacts, deposition of the semiconductor layer, and deposition of the gate electrode.

As the primary drawback of OMESFETs is a reliance on bulk rather than field-effect mobility. In the accumulation mode the field-effect mobility is much higher than the bulk mobility. Therefore higher on current, conductance and transconductance are expected in the OFET than those in the OMESFET.

To compare the performance of an OMESFET with an OFET we have simulated both devices using the same dimensions and materials. The organic semiconductor has to be specified for the simulation software. Since, in some aspects organics are different from crystalline semiconductors, we first review the energy structure and the model applied for conduction in organic semiconductors. The simulation results from the OFET and an OMESFET models are then presented.

C. Organic Semiconductors

The energy structure in organic semiconductors is different from that in crystalline semiconductors. In organics the highest occupied molecular orbital (HOMO) and the lowest unoccupied molecular orbital (LUMO) are analogous to the edges of the valence and the conduction bands, respectively [26]. The amorphous structure and the low energy of interaction between molecules in organic semiconductors leads to very narrow (or non-existent) energy bands, and localized states in the band gap [27]. Instead of bands with delocalized carriers, there can be a mobility edge, where the density of localized states is high and thus the effective carrier mobility is also high. Localized states also appear between the bands (or mobility edges) and affect conduction. Often there is a relatively high concentration of localized states. As a practical means of describing transport in these materials, Horowitz [10] has suggested the multiple trapping and release (MTR) model for conduction in organics. Carriers are assumed to be trapped in localized states, but they can be thermally released to the band (or mobility edge) for a short time until they are trapped again. Therefore the mobility is affected by the density of trap states and their energy difference from the band edge. For a single trap level the effective bulk mobility, μ_b , is obtained from [10]:

$$\mu_b = \alpha\mu_0 \exp\left(-\frac{\Delta E_t}{kT}\right) \quad (5)$$

where α is the ratio between the density of states at the edge of the energy band and the density of traps, μ_0 is the mobility in the delocalized states, ΔE_t is the activation energy of the trap (the energy difference between the trap level and the mobility edge), k is the Boltzmann constant and T is the absolute temperature. The MTR model is usually applied to study a device characteristic at a constant temperature e.g., room temperature. For the temperature dependency of parameters in a device more complicated models such as variable range hopping (VRH) are preferred [27]. The advantage of the MTR model is that an organic material can be modeled as a semiconductor provided that the density of states (DOS) is defined. Also, by knowing the DOS, some effects such as the Meyer-Neldel relation (MNR) are implicitly considered [28]. The experimental results well supports the application of the trapping model for DC analysis of organic devices at a constant temperature [11, 29].

Amorphous semiconductors usually behave like single-carrier semiconductors since the mobility of one type of carriers is often much lower than the other. Organic semiconductors with dominant hole mobility are called P-type and are usually more stable than N-type organic semiconductors when exposed to air [30]. The polymer modeled in this work (rr-P3HT) is P-type.

III. SIMULATIONS

Medici 4.0 (produced by Synopsys [31]) is used as the CAD tool for the device simulation. Medici models the two-dimensional distributions of potential and carrier concentrations in a device. The program solves Poisson's equation and the continuity equation in every node of a two-dimensional mesh determined by the user. The third dimension is always normalized to 1 μ m. Medici 4.0 implements the MTR model by considering localized states as traps.

A. Materials and Parameters

Regioregular- Poly 3 hexylthiophene (rr-P3HT), which is a very stable P-type polymer semiconductor [4], is chosen as the semiconductor for the simulated devices. Rr-P3HT has shown the highest field-effect mobility among the soluble organic semiconductors [32], making it a good candidate for printing. The band gap of this semiconductor is 1.7 eV [33]. The electron affinity is calculated to be 3.15 eV from the ionization energy and the band gap of rr-P3HT [34]. Since rr-P3HT is a P-type material, the simulation is done on holes as carriers and the effect of electrons is ignored. Therefore, only the density of localized states close to the valence band is considered. Table I lists the applied density of traps at 19 discrete levels which is intended to

mimic the density of states measured by Tanase et al [35]. In the MTR model, mobility of holes in the valence band is required (μ_0) [12]. Although μ_0 is not strictly known in rr-P3HT, the highest reported field effect mobility (0.12 cm²/Vs [32]), is used in the simulation in order to estimate performance under relatively optimum conditions. The dielectric constant is set to be $\epsilon_s=3$ [36], and the doping density is set at 1×10^{16} cm⁻³ [12].

In current printing technology, a good value for the thickness of a printed organic semiconductor layer is considered to be 400 nm [2]. For simplicity, gold with a work function of 5.1 eV, and aluminum with work function of 4.3 eV [37], are chosen for ohmic and Schottky contacts to the semiconductor, respectively [9]. In the OFET model, SiO₂ is chosen as the insulating layer, with a thickness of 100 nm [2]. All parameters and their references are listed in Table II.

B. OFET

The structure shown in Fig. 1 is used in the simulated OFET. The gate electrode, located at the bottom, is assumed to be made of aluminum, and the insulating layer is SiO₂ with a thickness of 100 nm. The drain and source electrodes are gold and are 4 μ m wide and 20 nm thick. The gap between the drain and the source is assumed to be 4 μ m which is actually the channel length of the transistor. In the simulations the channel width is normalized to 1 μ m, so the channel width to length ratio (Z/L) is 0.25.

The output characteristic of the OFET is shown in Fig. 3(a) for five different values of the gate voltage. Since the mobility of carriers in organics is found to be field dependent at electric fields higher than 10⁵ V/cm [10] the drain-source voltage is limited to 40 V to ignore the dependency of the mobility to the electric field. The output conductance (g_0) of the OFET in the linear regime is 5×10^{-11} Ω^{-1} , calculated from the slope of the plot when $V_{GS}=-40$ V at $V_{DS}=0$ V.

To study the transfer characteristics of the transistor the drain current is plotted versus the gate voltage in the linear regime ($V_{DS}=-0.5$ V), as shown in Fig. 3(b). A threshold voltage of -14 V is found for the transistor from the intercept of the asymptote to the voltage axis. Also, from the slope a mobility of 3.1×10^{-4} cm²/Vs is obtained, again using equation 1. Redrawing the curve in a semilog scale (Fig. 3(c)) shows a poor current on/off ratio (I_{on}/I_{off}) of 700, which is due to the thickness of the semiconductor. To be more like a switch, a transistor is required to have a high current ratio, which also reduces the static power dissipation in a logic circuit. The inverse slope of the plot at $V_{GS}=0$ V, known as subthreshold swing, is 4 V/decade, which is relatively large for a FET transistor [19] but typical of an OFET. The transconductance (g_m) in the linear regime is found from the slope of the plot at $V_{GS}=-40$ V to be $g_m=1.5 \times 10^{-12}$ Ω^{-1} .

The transistor characteristics are reasonably close to

those measured in printed OFETs [38]. A mobility of order of 10⁻⁴ cm²/Vs and a threshold voltage of -14 V are typical in a printed rr-P3HT OFET [38]. A current ratio of 100 in a printed OFET is achieved by Knobloch et al [38]. Also, normalizing the current in their transistor to $Z/L=0.25$ one obtains an output characteristic similar to Fig. 3(a). This similarity supports the choice of parameters to describe rr-P3HT.

C. OMESFET

The cross section of the device is shown in Fig. 2. Gold is chosen for drain and source electrodes and aluminum is used for the gate electrode. The same dimensions and materials that are applied in the OFET are used for the OMESFET in order to compare the performance of the two transistors. The thickness of each electrode is 20 nm and the channel length is 4 μ m. The gate electrode is assumed to be long enough not only to cover the channel area but also to extend over the drain and source electrodes. The semiconductor is rr-P3HT, with the same density of states as defined in Table I.

The Schottky contact is reverse biased in the OMESFET and a small current is passing through the gate. In this operating mode there is no need to consider special effects such as the space charge limited current (SCLC) [39] and/or the Meyer-Neldel relation (MNR) [28] for the Schottky contact.

The output and transfer characteristics of the OMESFET are plotted in Fig. 4. The output characteristics show both the resistive and saturation modes of the transistor, which confirms the occurrence of the pinch off in the transistor. Since the transistor works in depletion mode, it is on at $V_{GS}=0$ and application of a positive voltage to the gate switches the transistor to the off mode. $g_0=1 \times 10^{-13}$ Ω^{-1} is found from the plot at $V_{GS}=0$. In Fig. 4(b) the variation of the drain current versus the gate voltage at $V_{DS}=-0.5$ V is shown. The plot shows a subthreshold swing of 180 mV/decade, and the transconductance is $g_m=2 \times 10^{-14}$ Ω^{-1} .

I_{on}/I_{off} of the order of 10⁴ is achieved using a gate voltage range of 5 V. In spite of the fact that in OFETs the gate current is not a crucial parameter in DC characteristics, because of the insulating layer, the gate current in OMESFETs limits the performance of the devices. In Fig. 5, the gate current is plotted versus the gate voltage at $V_{DS}=-10$ V. The leakage current of the reverse biased Schottky junction between the gate and the semiconductor shows a current value in the order of 10⁻¹⁸ A. This current is small enough compared to the drain current to be ignored when the transistor is on. However, the off current for the transistor is in the same range as the gate current. Therefore it is expected that the off current would be reduced if the gate current is reduced.

In order to obtain G_0 the device is simulated in the absence of the aluminum layer. The I-V curve between the drain and the source terminals is plotted (Fig. 6). The slope

of the curve indicates that $G_0=1.24\times 10^{-13} \Omega^{-1}$. Given the doping density ($N=1\times 10^{16}\text{cm}^{-3}$) the bulk mobility is found to be $8\times 10^{-6} \text{cm}^2/\text{Vs}$, which is in good agreement with experimental values [40]. The bulk mobility is two orders of magnitude smaller than the field effect mobility.

IV. DISCUSSION

Table III summarizes the different parameters obtained from the simulation of the OFET and the OMESFET. The mobility in the OFET is about 40 times larger than the mobility in the OMESFET. Therefore the on current, the conductance, and the transconductance are larger in the OFET than those in the OMESFET. However, the I_{on}/I_{off} is more than an order of magnitude higher in the OMESFET than in the OFET. These results suggest that OFETs provide higher currents (important for certain applications including driving organic light emitting diodes) and probably faster response (due to the higher mobility). OMESFETs on the other hand offer low voltage and good on/off ratios in relatively thick devices suitable for printing.

In order to enhance the on/off ratio in the OFET, I_{on} can be increased by either increasing gate capacitance or by increasing the field-effect mobility (equations 1 and 2) and I_{off} can be reduced by applying a thinner layer of the semiconductor to reduce the bulk resistance [12]. Although a thin film of rr-P3HT with high mobility [41] and a thin film of insulator with large capacitance [7] can be produced by spin coating, the method is not compatible with printing low-cost electronics in a roll-to-roll process.

The lower mobility in the OMESFET causes smaller g_0 , g_m and I_{on} than those in the OFET. In order to enhance these parameters in the OMESFET, one can increase G_0 by increasing the semiconductor thickness and/or dopant density (equation 4). However, the desired pinch-off voltage determines the upper limit of G_0 as the voltage range extends with increases in the semiconductor thickness and the dopant density. In order to compensate the voltage range, affected by the increase in G_0 , a lower work function metal like calcium (WF=2.9 eV) might be applied. Also, the off current is likely reduced by application of a lower work function metal as a larger barrier is produced at the gate Schottky contact with the semiconductor [42]. Therefore, improvement of the on current and the current ratio in the OMESFET do not require a change in fabrication method to produce thinner films. In short, there are opportunities to improve the properties of the printed OMESFET over what has been simulated, but the OFET is unlikely to be made significantly better without improvement being made in printing processes.

The small range of voltage in the OMESFET is another advantage over the OFET. A standard 5V supply for TTL circuits is enough to drive an OMESFET, whereas the required supply voltage for an OFET is one order of magnitude larger for the same feature size. For the same

reason, the OMESFETs are much more suitable for battery operated circuits than the OFETs. Also, the small voltage range in the OMESFET reduces the power consumption of the transistor. Finally, the very small subthreshold swing in the OMESFETs makes them well-suited to logic circuits.

V. CONCLUSION

In this paper, we have proposed the MESFET structure for organic semiconductors as an alternative to OFETs when the cheap printing methods of fabrication are desirable. The results of the simulation predict the operation of OMESFETs with a current ratio of 10^4 in a voltage range of 5 V, which is better than the 700 times and 40 V of a thick OFET. Although the conductance and transconductance of the OMESFET are two orders of magnitude smaller than those of the OFET, in many situations these can be compensated in the OMESFET by using a thicker semiconductor film and/or using a more conductive semiconductor. The electrical characteristics of the OMESFET are suitable for low voltage, low power, inexpensive organic logic circuits.

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research involves fundamental studies and applications of polymer and nanotube actuators and electronic devices.



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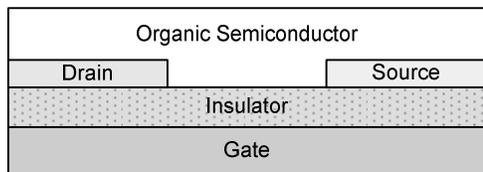


Fig. 1. Schematic of an OFET.

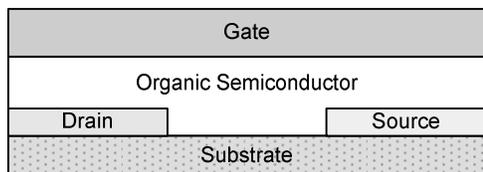
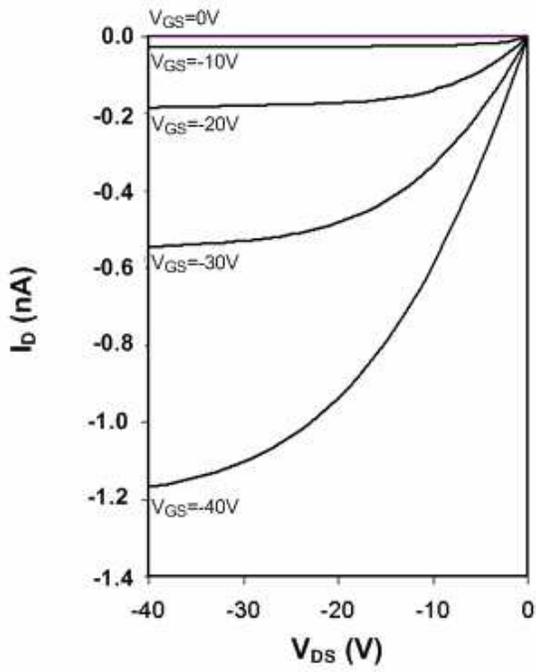
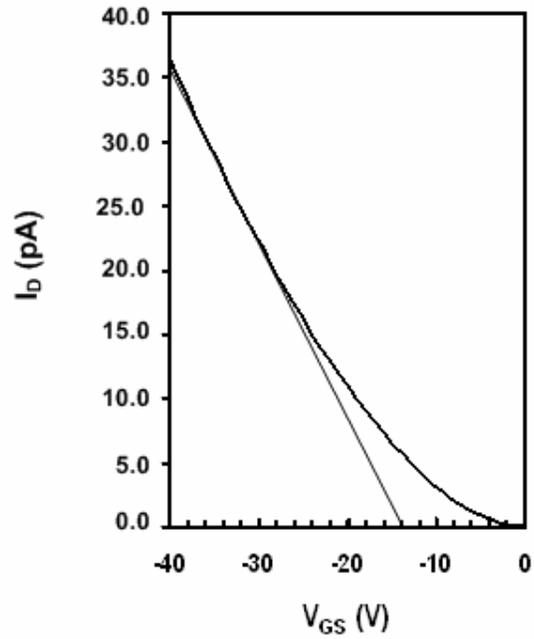


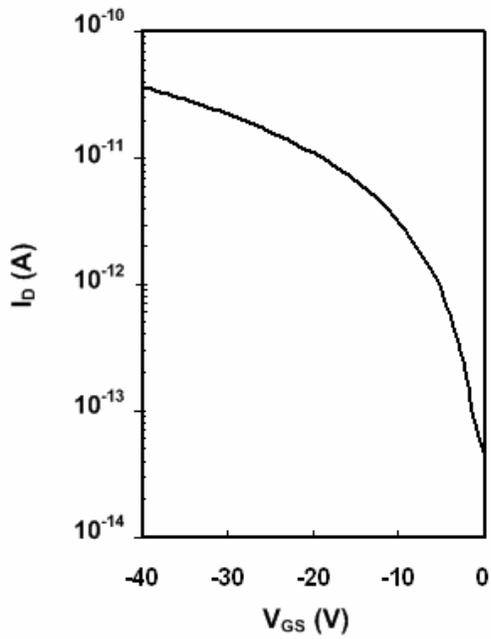
Fig. 2. The proposed geometry for Organic Metal-Semiconductor Field Effect Transistor (OMESFET).



(a)

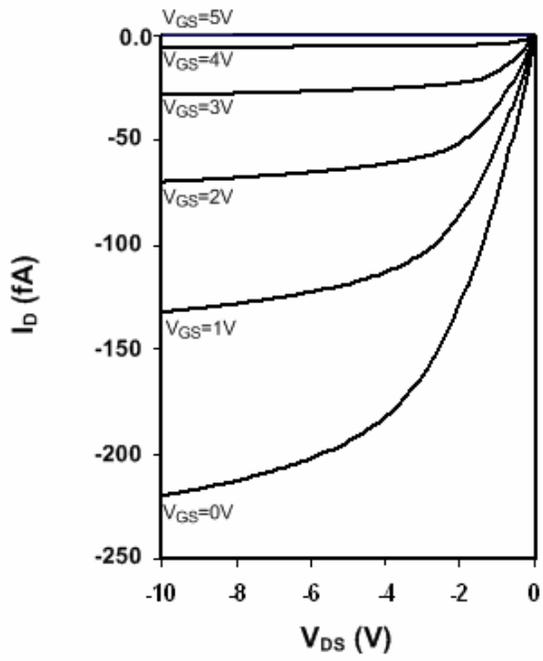


(b)

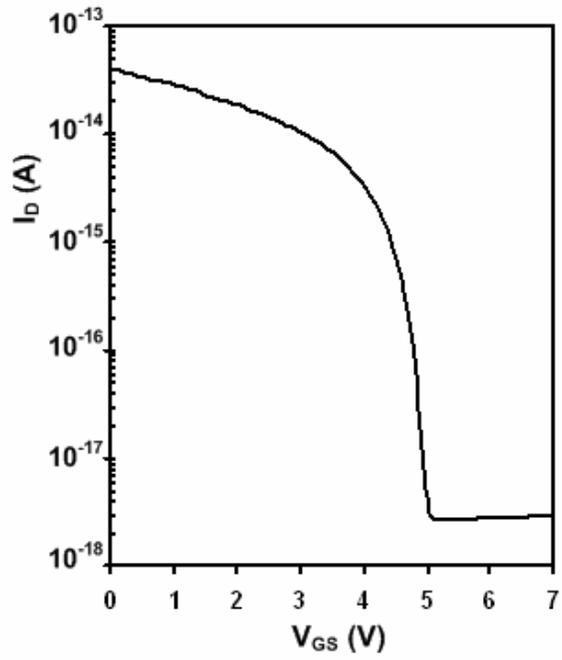


(c)

Fig. 3. (a) The output and (b,c) transfer characteristics ($V_{DS}=-0.5$ V) of the simulated OFET with a channel width of $1 \mu\text{m}$ and a length of $4 \mu\text{m}$. (b) is in a linear scale and (c) is in a semilog scale.



(a)



(b)

Fig. 4. (a) The output and (b) transfer characteristics ($V_{DS}=-0.5$ V) of the simulated OMESFET with a channel width of $1 \mu\text{m}$ and a length of $4 \mu\text{m}$.

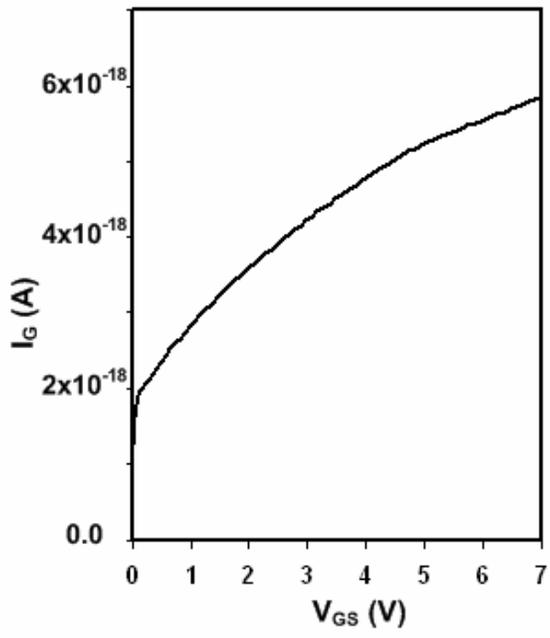


Fig. 5. The input characteristic of the simulated OMESFET.

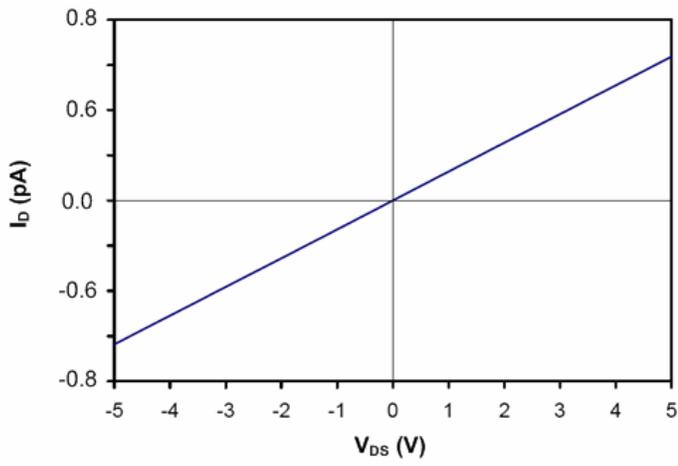


Fig. 6. The I-V curve between the drain and source terminals of the OMESFET in the absence of the gate contact. The slope indicates G_0 in the OMESFET.

TABLE I
DISCRETE LEVELS OF TRAP DENSITY RELATIVE TO THE EDGE OF VALENCE
BAND IN RR-P3HT

E_i	$E_i - E_V$ (eV)	Density of localized states ($\text{cm}^3 \cdot \text{eV}^{-1}$)
E ₁	0	1.00×10^{21}
E ₂	0.03	4.15×10^{20}
E ₃	0.06	1.72×10^{20}
E ₄	0.09	7.15×10^{19}
E ₅	0.12	2.97×10^{19}
E ₆	0.15	1.23×10^{19}
E ₇	0.18	5.12×10^{18}
E ₈	0.21	2.12×10^{18}
E ₉	0.24	8.82×10^{17}
E ₁₀	0.27	3.66×10^{17}
E ₁₁	0.30	1.52×10^{17}
E ₁₂	0.33	6.31×10^{16}
E ₁₃	0.36	2.62×10^{16}
E ₁₄	0.39	1.09×10^{16}
E ₁₅	0.42	4.51×10^{15}
E ₁₆	0.45	1.87×10^{15}
E ₁₇	0.48	7.78×10^{14}
E ₁₈	0.51	3.23×10^{14}
E ₁₉	0.54	1.34×10^{14}

TABLE II
THE LIST OF SET UP PARAMETERS FOR USED MATERIALS IN THE SIMULATION
OF THE ORGANIC TRANSISTORS

Material	Parameter	Symbol	Value	Unit	Ref.
rr-P3HT	Band gap	E_g	1.7	eV	[33]
	Electron affinity	χ_e	3.15	eV	[34]
	Permittivity	ϵ_s	3		[36]
	Dopant Density	N_S	1×10^{16}	cm^{-3}	[12]
	Mobility	μ	0.12	cm^2/Vs	[32]
	Thickness	t_s	400	nm	[2]
Metals	Au work function	ϕ_{Au}	5.1	eV	[37]
	Al work function	ϕ_{Al}	4.3	eV	[37]
Insulator	SiO ₂ thickness	t_{ins}	100	nm	[2]
	SiO ₂ permittivity	ϵ_{ins}	3.9		[20]

TABLE III

ELECTRICAL CHARACTERISTICS OF THE SIMULATED OFET AND OMESFET

Parameter	OFET	OMESFET
I_{on}/I_{off}	700	10^4
Gate voltage range (V)	40	5
Threshold/Pinch-off voltage (V)	14	5
Subthreshold swing (mV/decade)	4000	180
Mobility (cm^2/Vs)	3.1×10^{-4}	8×10^{-6}
g_o (Ω^{-1})	5×10^{-11}	1×10^{-13}
g_m (Ω^{-1})	1.5×10^{-12}	2×10^{-14}
I_{on} (A) @ $V_{DS} = -0.5\text{V}$	3.5×10^{-11}	4×10^{-14}